

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/500,214 Confirmation No. : 2535  
First Named Inventor : Takuya SUGAWARA  
Filed : June 28, 2004  
TC/A.U. : 2823  
Examiner : M. Estrada  
  
Docket No. : 010986.55104US  
Customer No. : 23911  
  
Title : Substrate Treating Method and Production Method for  
Semiconductor Device

**REPLY**

**Mail Stop RCE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in accompaniment of a Request for Continued Examination and in response to the Final Office Action dated February 3, 2006, the period for response having been extended to July 3, 2006 by the attached Petition for Extension of Time.

**Amendments to the Specification** are discussed on page 2 of this paper. A Substitute Specification with marked-up version is submitted concurrently herewith.

**Remarks** begin on page 3 of this paper.

An **Appendix** including a substitute version of the specification, and a marked up version of the specification is attached following page 6 of this paper.